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# IMPROVED CHARGE INJECTION DEVICE AND A FOCAL PLANE INTERFACE ELECTRONICS BOARD FOR STELLAR TRACKING

# **Final Technical Report (August 17, 1982 to January 31, 1984)**

G.J. Michon and H.K. Burke

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# IMPROVED CHARGE INJECTION DEVICE AND A FOCAL PLANE INTERFACE ELECTRONICS BOARD FOR STELLAR TRACKING

G.J. Michon and H.K. Burke

## 1. INTRODUCTION

The objectives of this program were to develop an improved Charge Injection Device (CID) stellar tracking sensor and to deliver an operating sensor in a control/readout electronics board. The sensor consists of a shift register scanned,  $256 \times 256$  CID array organized for readout of  $4 \times 4$  sub-arrays. The  $4 \times 4$  sub-arrays can be positioned anywhere within the  $256 \times 256$  array with a 2-pixel resolution. This allows continuous tracking of a number of stars simultaneously, since nine pixels ( $3 \times 3$ ) centered on any star can always be read out. Star centroids have been located to a resolution of 2 percent of the pixel spacing of 20 microns using a previously developed CID sensor with the same organization [1].

A number of basic CID image sensor improvements have been developed at the General Electric Company as a result of on-going CID programs. These improvements include increased quantum efficiency resulting from reduced electrode masking and anti-reflection coatings; reduced fixed pattern noise levels through the development of fine grain polysilicon electrodes and a reduction in electrode cross-over area; increased dynamic range for extended objects through the use of a clamp scanner to maintain voltage of unselected array row electrodes; reduced on-chip preamplifier transistor low frequency (I/f) noise through the use of the  $<100>$  crystal orientation and improved row and column select scanner design. The control/electronics board provides the interface between the sensor and a microcomputer. The board contains the drivers to convert TTL logic levels to the MOS voltage levels, amplifiers and sample and hold circuitry for signal conditioning, an analog multiplexer to route the four parallel output channels through one analog-to-digital converter, and the analog-to-digital converter. The sensor is mounted on a thermoelectric cooler that is within the hermetically-sealed package. Temperature control circuitry for the sensor is on the electronics board. Low noise power supply regulators are also mounted on this board.

## 2. PROGRAM HISTORY

A  $128 \times 128$  CID imager organized for  $4 \times 4$  sub-array addressing and using multiple nondestructive readout for low noise operation was developed under NASA sponsorship in 1978 [2]. Subsequently, the first  $256 \times 256$  CID star tracker sensor was designed and fabricated using General Electric internal funding. This program was initiated in August 1982 to fabricate a sensor incorporating improvements in design and silicon processing and to supply the interface control electronics required to operate the sensor.

The sensor, designated ST256E, was designed and the topological layout completed in 1982. An internal topological layout design review was held on November 30, 1982, and after changes were made to increase the aluminum conductor spacing to a more conservative value, the final pattern generation tape was written.

The mask fabrication facility at the Syracuse, New York, General Electric plant had been shut down and was being moved to a new location in late 1982. This facility had been used to fabricate most CID imager masks in the past. An outside mask vendor was consequently needed and Qualitron of Danbury, Connecticut, was chosen. This mask set was the first CID imager set fabricated by this vendor, but there were no problems with mask quality. The

design of the sensor and the identification of an outside mask vendor, however, had taken longer than expected. The delay was caused, in part, by a move of the design group and computer aided design equipment (Calma computer graphics and a VAX super minicomputer) to a new electronics building at Corporate Research and Development. Masks were ordered on January 11, 1983. The completed mask set was received on February 9, 1983, and a 16-wafer lot, designated STS-3 was started into processing on February 16, 1983. The design of the focal plane electronics was also completed during February. Lot STS-3 was lost during processing because of phosphorus contamination during an  $N^+$  doping step and a replacement lot, numbered STS-4, was started on March 8, 1983. Lot STS-4 was completed during the last week of June and probe testing was promptly started.

About this time, the contract was extended to include the delivery of a second focal plane electronics board and an additional sensor.

All the parts needed to assemble an all-solder joint, hermetically-sealed sensor package with an integral thermoelectric cooler were received. The maximum temperature the thermoelectric cooler can withstand is 130° C. It was necessary to develop an assembly procedure, using low temperature solders, that would allow soldering the cooler to the header, the imager chip carrier to the cooler, and hermetically seal the package cover to the header and the cover glass.

Imagers selected at probe test were bonded and wired into chip carriers and then screened for low cosmetic defects, mainly localized pixels with high dark current (bright spots). The best five sensors were then assembled with thermoelectric coolers into the final package.

The sensors were then evaluated for spectral quantum efficiency, temporal noise, fixed pattern noise, and dark current prior to delivery.

### 3. SENSOR DESIGN

#### 3.1 Organization and Operation

A block diagram of the sensor is shown in Figure 1. During operation, the Vertical Select Scanner is used to address four adjacent rows for readout. These rows, and the compensation row, at the top of the array, are routed to five on-chip transistors. The Clamp Scanner is a duplicate of the Vertical Select Scanner. Clamp Scanner outputs are inverted so that all rows but the addressed rows are connected to the row clamp voltage, RE. The Horizontal Select Scanner is used to address four array column electrodes which are driven by the four enable inputs, EN1 through EN4. This sensor organization allows 4×4 sub-arrays of pixels to be addressed for readout.

The array is cleared of charge by injecting all sensing sites in parallel. This is accomplished by energizing the CVG input to connect all column electrodes to the CVD terminal. When the clamp scanner is cleared (all zeros), all row electrodes are connected to the row clamp terminal, RE. All rows and columns are then driven to their minimum voltage level to effect injection.

A schematic diagram of the array is shown in Figure 2. The vertical select, clamp, and horizontal scanners are two-phase, bootstrapped, ratioless MOS shift registers. The last stage register outputs are brought out to pads for probe testing only; they are not normally wired to package pins. Decoders have been placed between each register stage output and the array selection switches so that the 4×4 sub-array addressed can be positioned with two pixel resolution. The control inputs for these decoders are labelled U and D (up and down) for the vertical decoders, and R and L (right and left) for the horizontal decoder.

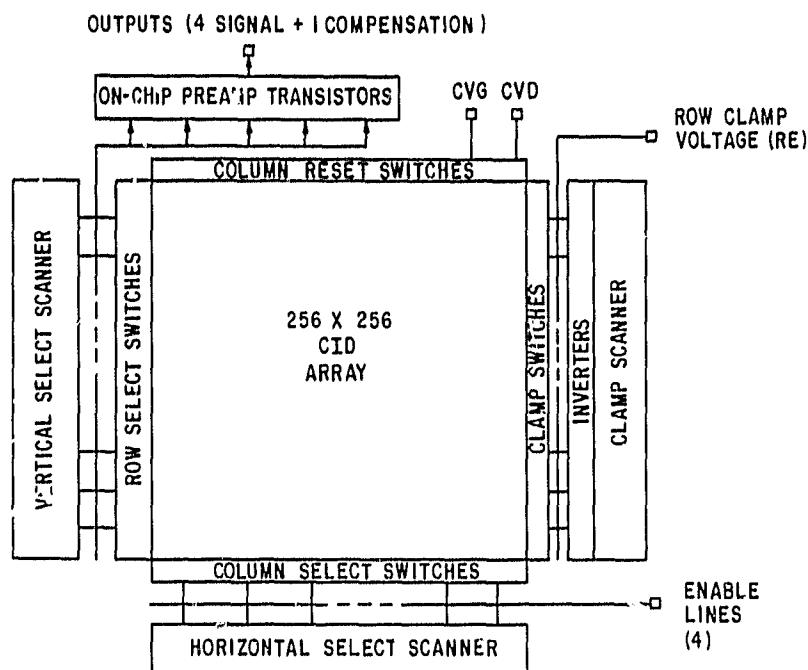


Figure 1. ST256E Block Diagram

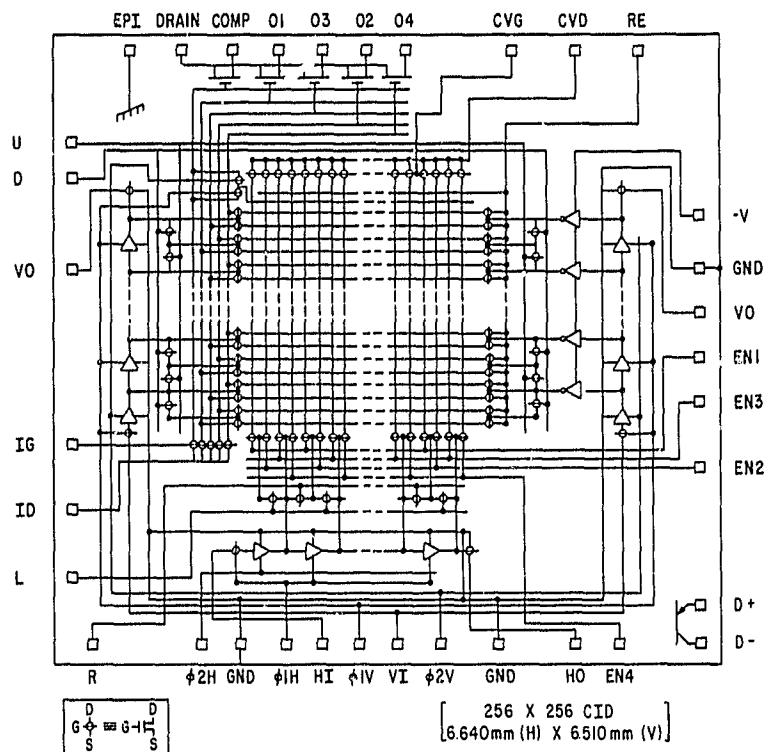


Figure 2. ST256E Schematic Diagram

### 3.2 Improvements

The major electrical design improvements made in this sensor over the previous ST-256D design are detailed below:

1. Scanner Design - The internal node capacitance of the scanners has been trimmed to increase the parameter margins (clock voltage, transistor threshold voltage, etc.) over which reliable operation can be obtained.
2. Clamp Scanner - The clamp scanner has been added so that voltage can be maintained on all unaddressed array row electrodes. This improves dynamic range when extended objects are being imaged by preventing the photocurrent at unaddressed pixels from discharging the row conductors.
3. On-Chip Preamplifier Transistor - MOS transistors, connected as source followers, have been added in series with each output line. This change should greatly reduce interference from associated electronic circuits by keeping the sensitive signal lines completely within the sensor chip. The topological layout of the sense lines has been balanced to maintain equal capacitance on all signal output lines.
4. Compensation Line - The 257th row, at the top of the array, is used as a compensation line to reduce the dynamic range requirements of the off-chip amplifier, sample-hold circuitry. This line is connected to the negative input of the four signal differential amplifiers. In previous designs, there have been problems in obtaining completely satisfactory operation using this compensation technique. If the compensation line is made identical to all other array rows, it is photosensitive and can cause interference when illuminated. If there is no charge storage region provided for the compensation line pixels, the line capacitance is different than other array lines. In this design, the compensation line is made identical to other array lines but a drain (collector) region has been added adjacent to each compensation line pixel so that any charge collected is drained off. The drain line is connected to RE (Figure 2). In order to completely balance the capacitance of the compensation channel with the signal channels, two row selection switches have been added in series with the compensation line. When either switch is energized by either  $\phi 1V$  or  $\phi 2V$ , the compensation line is connected to the compensation output bus. The topological detail of this circuitry is shown in Figure 3. In addition, extra row selection switch transistors with total transistor capacitance equal to the active row selection switch transistor capacitance have been added to the compensation output bus to achieve a total capacitance balance.
5. Narrow Electrodes - The primary cause of fixed pattern noise in CID imagers has been traced to variations in the crossover capacitance between row and column electrodes. Since the charge storage capacity of the row and column electrodes is a direct function of electrode width, and the crossover capacitance is a function of the electrode width squared, the signal-to-fixed-pattern noise ratio improves as electrode width is reduced. The electrode size chosen for this design is shown in Figure 4. This structure has  $\approx 55$  percent of the storage capacitance of the ST-256D design with a field oxide isolation; 80 percent with channel stop isolation. The row-column crossover capacitance has been reduced by a factor of 4.

The major semiconductor process improvements planned for device fabrication are detailed below:

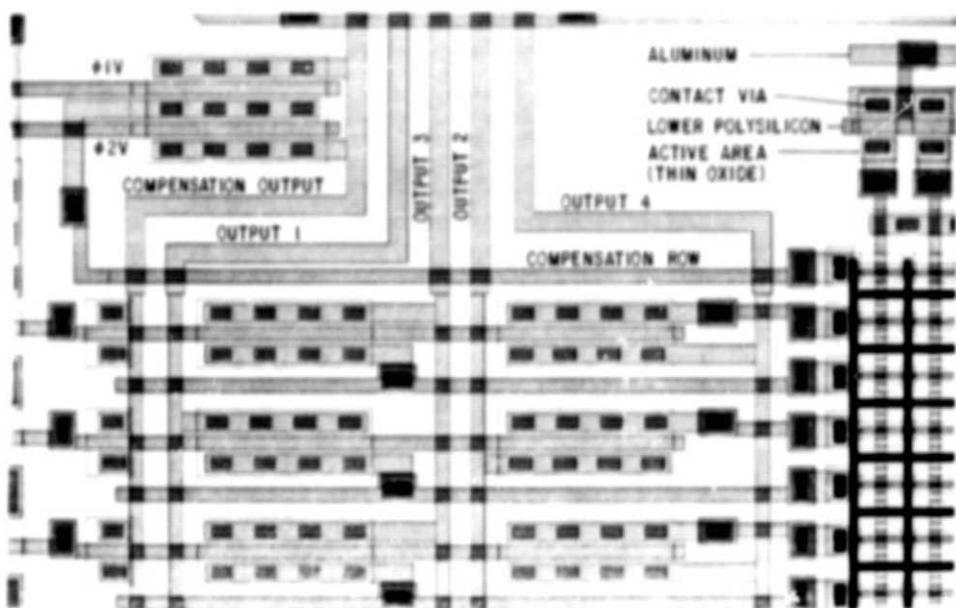


Figure 3. Signal Compensation Bus Topological Layout

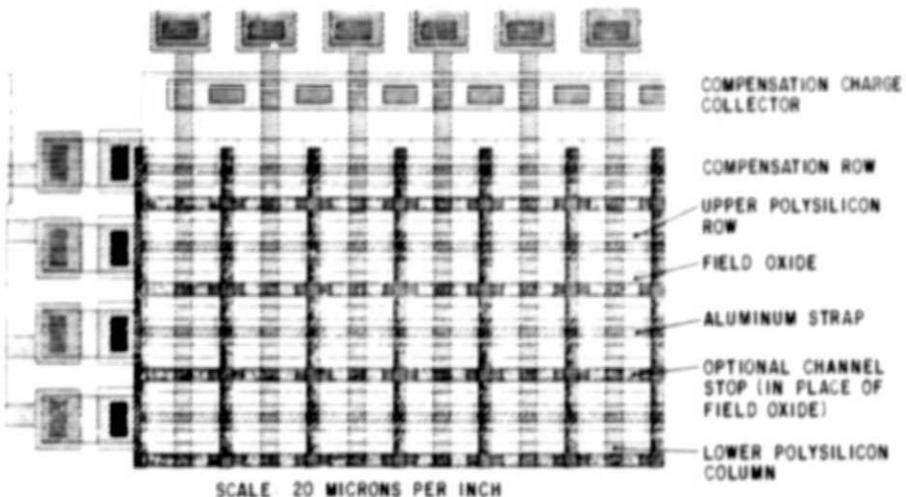


Figure 4. Array Topology

1. Thin Oxide Implant - The exposed thin oxide regions in the array (the thin oxide not covered with electrodes) will be implanted to set the threshold voltage of these regions above the electrode operating voltages. This prevents any surface charging from affecting array operation.
2. Fine Grain Polysilicon - Processes developed to achieve fine grain polysilicon electrodes will be used. This fine grain structure reduces the row-column crossover capacitance variations and, as a result, reduces fixed pattern noise.
3. Channel Stops - Mask levels have been included in this imager design to retain the option of using implanted channel stops in place of the thick field oxide to provide isolation

between adjacent sensing sites. The use of channel stops to achieve a higher, more uniform spectral responsivity is presently being explored at the General Electric Company on other programs. If this approach proves successful, this option can be exercised at a later date.

4. Anti-Reflection Coating - An aluminum patterning process which does not result in a lift-off glass residue layer is planned for these sensors. An anti-reflection silicon nitride layer can then be applied directly on the upper polysilicon electrode to enhance responsivity.

#### 4. SENSOR PACKAGE DESIGN

In order to obtain maximum performance from these CID sensors, it is necessary to cool the devices to reduce dark current levels. At room temperature, dark current shot noise is the dominant temporal noise. Spatial variations in dark current are a significant fixed pattern noise source, particularly localized regions of high dark current (bright spots). If the sensor is cooled below the dew point of its atmosphere the moisture that condenses on the surface of the chip will cause a malfunction. The sensor will recover from a short exposure to a small amount of moisture. In at least one case, however, where the chip was operated for an extended period with liquid water condensed on its surface, the aluminum conductors were destroyed. A hermetically-sealed package is clearly called for in this application.

The sensor packaging procedure has to satisfy a number of requirements. We have not been able to evaluate the sensor low light level performance at wafer probe. It has been necessary to package chips that pass wafer probe in chip carriers so they can be screened prior to assembly onto the thermoelectric coolers. The thermoelectric cooler has been placed within the sensor package to minimize convection heat loss and to keep the glass window free of condensation. An all-solder joint assembly has been chosen to insure that the package is hermetic. The maximum temperature that the thermoelectric cooler can withstand is 130° C. It was necessary to develop an assembly procedure, using low temperature solders, that would allow soldering the cooler to the header, the imager chip carrier to the cooler, and hermetically seal the package cover to the header and to the cover glass.

Normal chip carriers have their contact points on the rear surface and a sealing ring for the cover on the front (chip mounting) side. A custom chip carrier was designed with the contact points on the front surface and the rear surface metallized for solder mounting on the thermoelectric cooler. The drawing of this carrier is shown in Figure 5; the wiring diagram from the chip to the chip carrier, and from the chip carrier to the Tekform header is shown in Figure 6. After the imager is bonded and wired into the chip carrier, the rear of the carrier is tinned with 118° C solder (Indalloy\* #1). The Marlow type thermoelectric cooler (purchased with pretinned surfaces) is then reflow soldered to the chip carrier. The Tekform type header is then pretinned in the thermoelectric cooler mounting region with Indalloy #1 solder and reflow soldered to the cooler/chip carrier assembly. The outer edge (cover attaching region) is pretinned at this time with the same solder. An electric discharge technique was used to cut out the window without distorting the cover. After deburring, the edge of the cutout and the Millis metallized glass lids are pretinned with Indalloy #2 (142° C) solder, reflow soldered and given a helium leak check. The edge of the cover is then tinned with Indalloy #1. The parts are then vacuum backed at 100° C for 1 hour and the cover is reflow soldered to the header in a glove box containing 90 percent forming gas and 10 percent helium. The sealed package is then given a helium leak check.

The assembled sensor is shown in Figure 7 before the cover is attached. A heat sink must be used in contact with the rear surface of the Tekform header to remove the heat generated by the thermoelectric cooler, about 5 watts maximum.

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\* Trademark of Indium Corporation of America, Utica, NY, for low melting point alloys.

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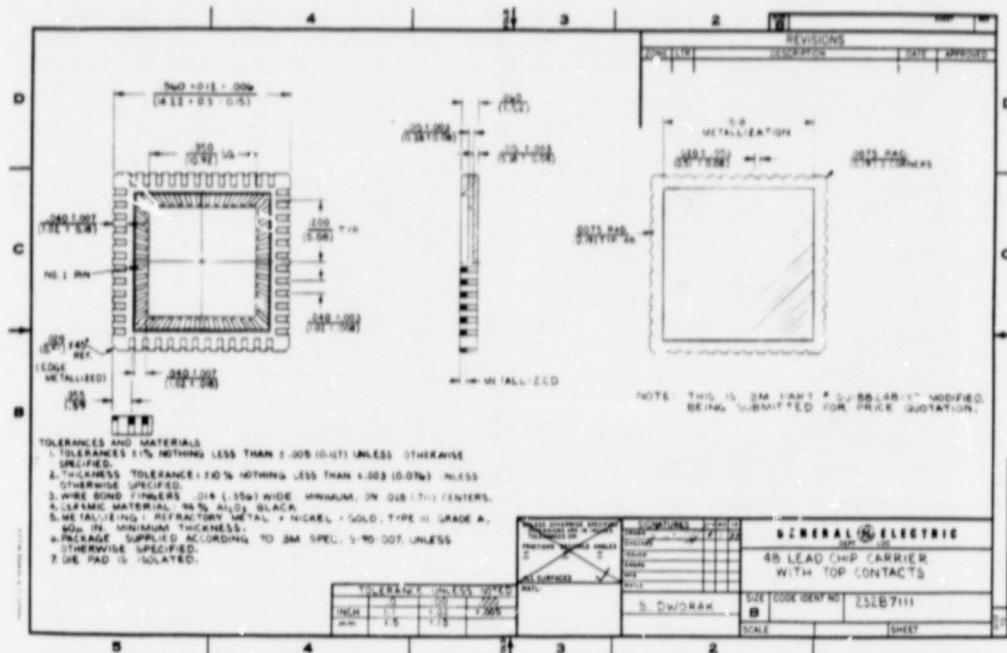


Figure 5. Custom 48 Lead Chip Carrier

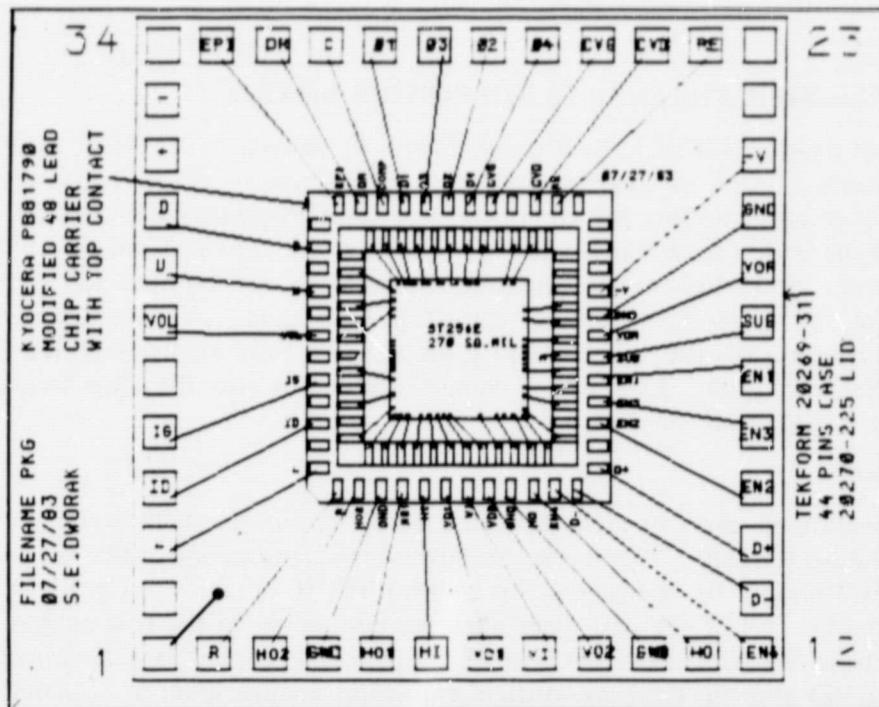


Figure 6. Imager and Chip Carrier Wiring

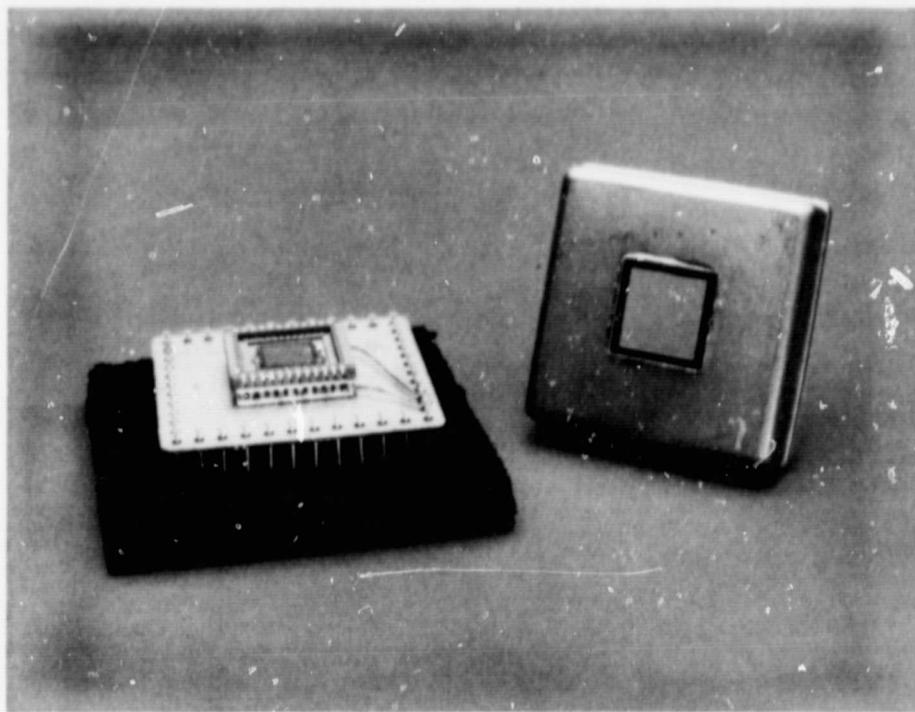


Figure 7. Sensor Assembly

## 5. FOCAL PLANE INTERFACE ELECTRONICS BOARD

An overall diagram of the electronics board is shown in drawing number 152D6254 (ST256E Camera), a copy of which is appended to this report. TTL level timing signals from the controlling microcomputer are converted to the appropriate MOS voltage levels to drive the sensor. Type 139CJ level converters along with series resistors and clamp diodes are used for this purpose. Four differential amplifiers boost the sensor output signals which are then sampled using the correlated double sampling technique. A programmable operational amplifier, with a gain of unity, is used to multiplex the four analog sampled signals into the analog-to-digital converter. Low noise voltage regulators and the chip temperature control servo are also included on this board.

### 5.1 Sensor Drive

Frame injection is used to clear all array pixels simultaneously at the beginning of the charge integration period. This is accomplished by connecting all array columns to the column VD (CVD) pin by energizing the column VG (CVG) control pin with a -20 volt signal (see Figure 2). All of the row electrodes are connected to the row enable (RE) pin since the clamp scanner was cleared at the end of the previous frame. Injection is effected by driving both the CVD and the RE pins to their minimum voltage level of -2 volts. At the end of the injection pulse (about  $100 \mu\text{sec}$ ), the columns and rows are returned to their charge integration levels, CVD to -17 volts and RE to -8 volts. The CVG pin is then switched off (to 0 volts).

Column and row shift registers, in conjunction with the right/left (R/L) and up/down (U/D) control lines, are then scanned to select the desired  $4 \times 4$  sub-array. The shift registers use non-overlapping 2-phase clock signals, that switch between -2 and -17 volts. Horizontal

and vertical input pulses (HIN and VIN) are clocked into the registers by the 01H and 01V clock pulses respectively. The R/L and U/D pins are driven between 0 and -20 volts.

The  $4 \times 4$  sub-array is read out by driving the four enable lines (E1 through E4) in time sequence. Each enable line can be driven as many times as required, with each pulse effecting one non-destructive readout operation. The IG pin is pulsed to -14 volts at the beginning of each column drive cycle to reset the signal lines to the ID reference level of -8 volts.

At the end of the readout interval, the shift registers are cleared by driving the horizontal and vertical phase lines with the proper number of pulses. The next frame can commence at this time.

## 5.2 Low Noise Amplifiers

A schematic of the low noise amplifiers is given in drawing number 196C4204, which is appended to this report. The sources of the five on-chip transistors are connected to source load resistors (8.2K each) at inputs C and 1 through 4. These signals are capacitively coupled to four 2N5565 junction fet pairs connected as differential source followers. The difference signal between the four input signals (1,2,3,4) and the compensation signal (C) is taken by the four AD818/NE5534 differential amplifiers. The gain of each channel is set to 100 by selecting the AD818 emitter-to-emitter resistors.

## 5.3 Post Amplifiers/Sample and Hold

Readout of the CID sensor requires the use of correlated double sampling to control KTC noise. During each readout cycle, the imager row and output multiplex signal line (on-chip) is reset by the IG pulse and allowed to float. Since this line has a capacitive source impedance, this reset operation introduces a KTC offset noise after each reset pulse. A sample of this offset, after amplification, is stored on the 0.01 ufd input capacitor to the LF298 sampler when the RESTORE pulse is applied (see drawing 152D6254). Since this sample of the KTC offset is in series with the signal, it is automatically subtracted from the imager output. The selected column is then driven to transfer charge from the column to the row electrode. The resulting signal is then sampled by the HA2425 sampling circuit. This sampling circuit has a gain of 10 to give an overall signal processing gain of 1000 before the analog-to-digital converter.

## 5.4 Multiplexer, Analog-to-Digital Converter

A programmable operational amplifier, HA2405, has been connected as a unity gain, non-inverting follower to multiplex the four parallel output samples into one analog-to-digital converter. A Micronetworks type MN5245 12 bit analog-to-digital converter, connected for a 0 to +5 volt input range, is connected to the output connector with type SN74365 non-inverting drivers. The SN74366 inverting drivers can be used if an inversion is needed at the digital output.

## 5.5 Sensor Temperature Control

The schematic of the temperature controller, drawing number 179C4307, is appended. An on-chip silicon diode is used to measure sensor temperature. This diode is forward biased at 100 microamps to generate approximately 600 millivolts at 25° C. Its temperature coefficient is very close to -2 millivolts per degree celsius. The 5K temperature set potentiometer output voltage is compared with the temperature sensing diode voltage using a fet input operational amplifier (TL081) connected as an integrator. A 5 second time constant lead has been inserted in the feedback path to stabilize the system. The amplifier output has been clamped to +5

volts maximum to keep the integrator from going to its internal voltage limit of +12 volts when in saturation. The system would have a very long saturation recovery time at the higher saturation voltage. An optocoupler, type 6N139 connects the amplifier output to the power transistor that drives the thermoelectric cooler. A second TL081 is used to generate a -10 mv/ $^{\circ}$  C for data logging purposes. Finally, a 741 operational amplifier with a gain of 0.1 and proper offset is used to indicate chip temperature. Its scale is 1 millivolt per degree celsius, with 25  $^{\circ}$  C equal to +25 millivolts.

## 6. TEST RESULTS

### 6.1 Wafer Probe Tests

The first three wafers from lot STS-4 were probe tested using an existing probe camera. The functional yield was high. Wafer #6 yielded 24 imagers; wafer #8 yielded 9 imagers; and wafer #9 yielded 21 imagers. This is an overall functional yield of 23%. Fourteen imagers were selected for packaging into chip carriers. The main cosmetic defect encountered was localized regions of high dark current, i.e., bright spots.

### 6.2 Chip Carrier Mounted Sensor Screening

The imagers mounted in chip carriers were operated in the Focal Plane Interface Electronics Board to further screen these devices so that the better ones could be assembled onto thermoelectric coolers in the final package for evaluation and delivery. These devices were operated at room temperature. The dark field image produced by one of these devices is shown in Figure 8; the bright spots visible at room temperature are normally cool out when these sensors are operated below 0  $^{\circ}$  C. The image is broken into six segments because the microcomputer used to operate the Focal Plane Interface Electronics Board did not have enough memory available to store the complete image.

Temporal noise and histogram data on bright spots was used to select the best devices for final packaging.

### 6.3 Packaged Sensor Evaluation Results

In order to properly evaluate the performance of these sensors, it was necessary to calibrate the transfer function of the system from the incident photon flux to the digital output. A block diagram of the system is shown in Figure 9. Spectral quantum efficiency defines the ratio of the charge (expressed in electrons) collected and stored in the CID image sensing array to the incident photons, as a function of wavelength. The readout efficiency is the fraction of the collected charge that appears on the CID output capacitance upon readout. The total gain is the product of the on-chip source follower gain and the differential amplifier gain. Once the transfer function from stored charge in the array to the output is known, spectral quantum efficiency can be measured, and noise and dark current levels can be measured in terms of either incident photons or photoelectrons.

#### 6.3.1 Readout Efficiency

Charge is stored in a CID imager in inversion layers of MOS capacitors as diagrammed in Figure 10. Prior to readout, with -17 volts applied to the column electrodes and -8 volts applied to the row electrodes all of the signal charge is stored under the column electrodes, Figure 10a. During readout, when the column voltage is switched from -17 volts to -2 volts, the signal charge transfers from under the column electrode to under the row electrode, Figure 10b. A capacitive charge divider exists between the silicon surface and the row electrode (oxide capacitance), and the silicon surface and the substrate (silicon depletion capacitance), Figure 10c. Most of the transferred charge appears on the row electrode as a displacement

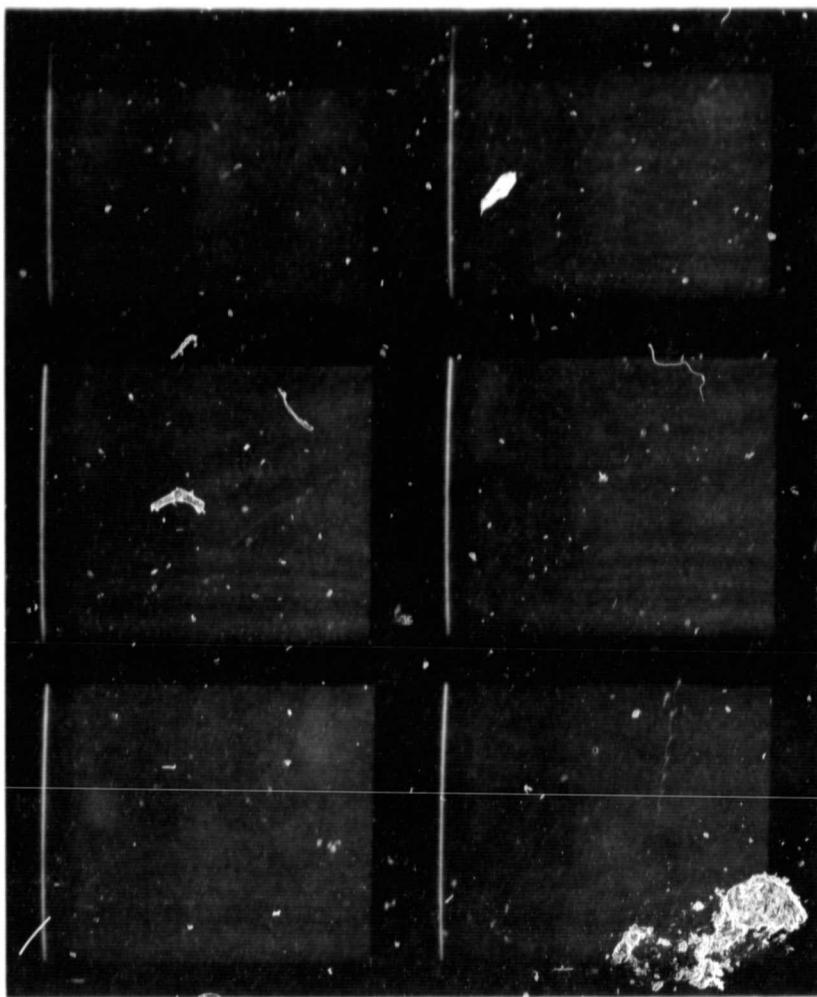


Figure 8. Typical Dark Field Image

charge because the oxide capacitance is larger than the silicon depletion capacitance. The fraction that appears on the row electrode is called the readout efficiency. In the absence of edge fringing effects, this fraction is .94 for the structure used in these imagers (910 angstrom equivalent oxide thickness, 10 ohm-cm N-type substrate doping level). Readout efficiency can be calculated taking edge fringing effects into account, but certain details concerning the edge effects (surface doping of the silicon, shape of the field oxide-thin oxide interface, etc.) are not well known with the result that this calculation is not very accurate. The readout efficiency can be measured directly on the ST256E sensor because a drain was placed adjacent to the compensation line. This drain, the compensation charge collector in Figure 4, can be used to directly transfer charge to and from the compensation row inversion layers, and the fraction of this charge that appears on the compensation line can be measured. The measured readout efficiency of device STS-4-6-30 was .747.

The output capacitance (on-chip) was measured to be 10.8 pf, and the on-chip source follower gain, with an 8.2K load resistor, was 0.907. The full scale capability of this system is 500,000 electrons, and the scale factor is 122 electrons/LSB.

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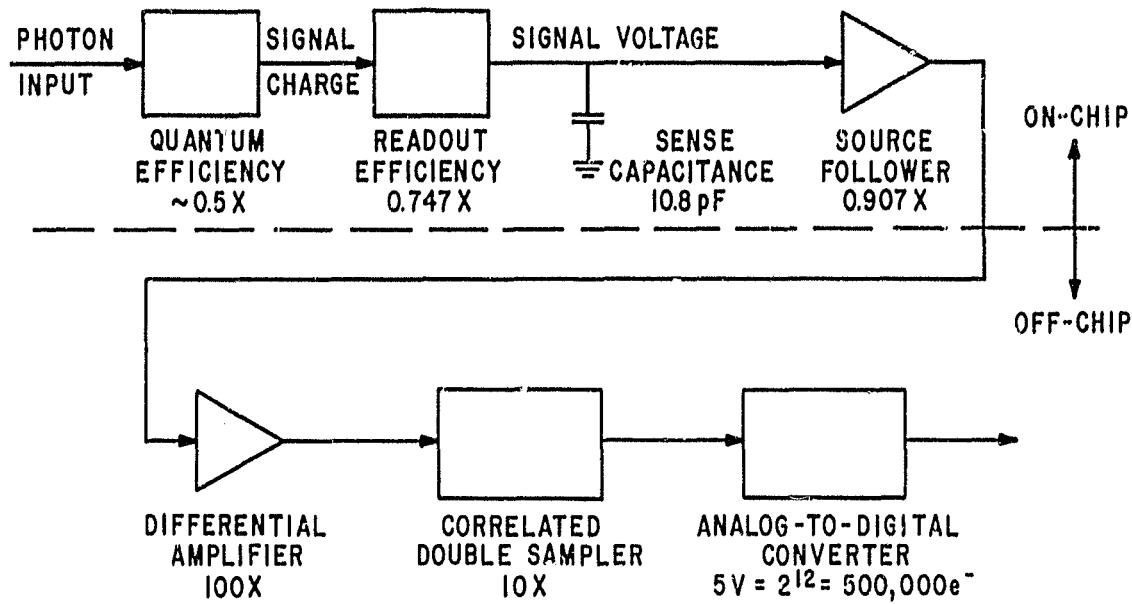


Figure 9. System Transfer Function

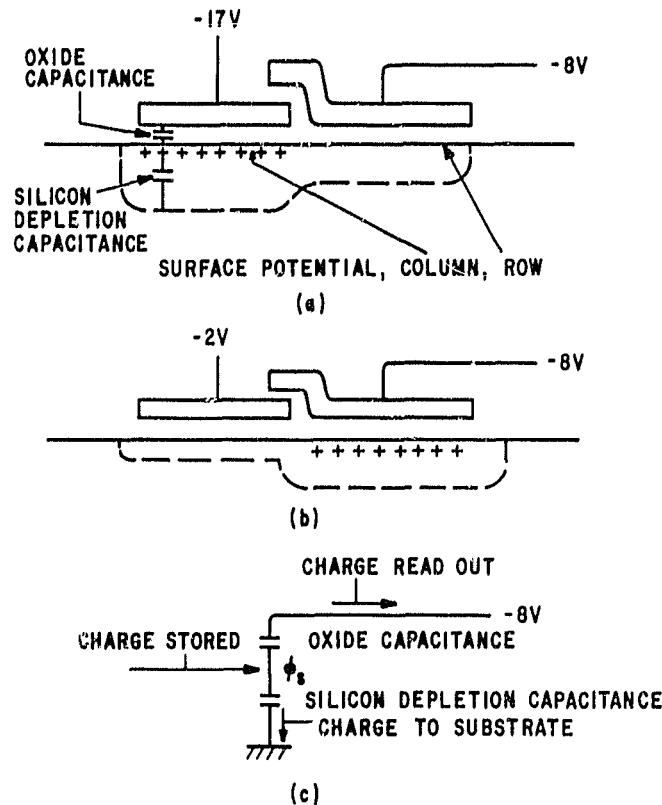


Figure 10. Readout Efficiency

### 6.3.2 Spectral Quantum Efficiency

Spectral quantum efficiency was measured using a Bausch and Lomb grating monochromator and a UDT silicon diode detector as a reference. This silicon reference diode was calibrated against a reference diode calibrated by the National Bureau of Standards. Figure 11 shows measured spectral quantum efficiency for two sensors from lot STS-4, wafer 6, one without the package cover glass (#24), and one with cover glass (#26). The cover glass is not anti-reflection coated and causes about an 8% reflection loss. One device from wafer 9 (#STS-4-9-26) was given an extended spectral response measurement, from 200 nM in the UV, to 1100 nM, Figure 12. A vacuum photodiode was used as a reference in the uv region, from 200 nM to 400 nM.

### 6.3.3 Temporal Noise

The temporal noise sources in CID imagers have been evaluated in a previous study [3]. The significant noise sources in this device are KTC noise introduced by resetting the sense line capacitance, the row selection switch resistive noise, and amplifier noise. Noise generated in the row conductors is negligible because the polysilicon rows have been strapped with high conductivity aluminum. Correlated double sampling is used to suppress the KTC noise [4]. The Johnson noise contributed by the row select switch and amplifier transistors is given in Table 1. Each noise voltage has been referred to the on-chip sense line.

In addition to Johnson noise, the on-chip MOS source follower transistors exhibit excess low frequency noise commonly called 1/f noise. The mean value of on-chip transistor noise measured on two devices from each of wafers #6, 9, and 11; lot STS4, is plotted in Figure 13. The 1/f model of this noise is shown dashed in this figure.

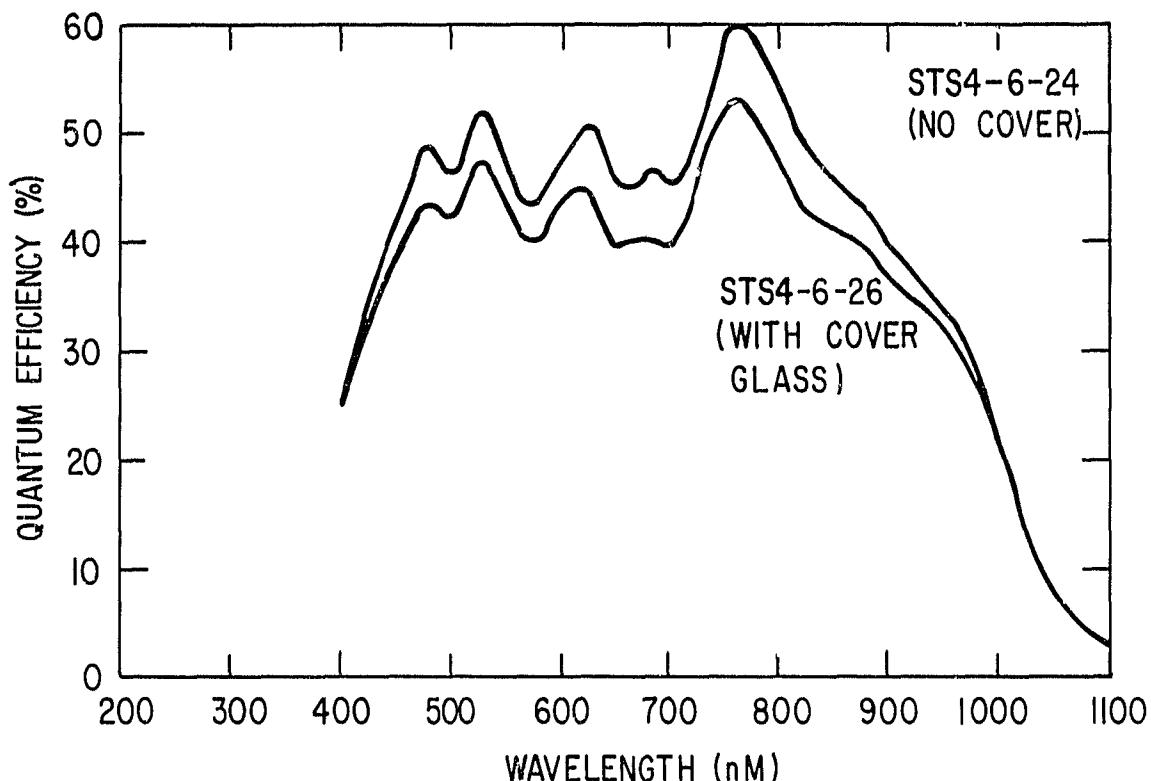


Figure 11. Spectral Quantum Efficiency

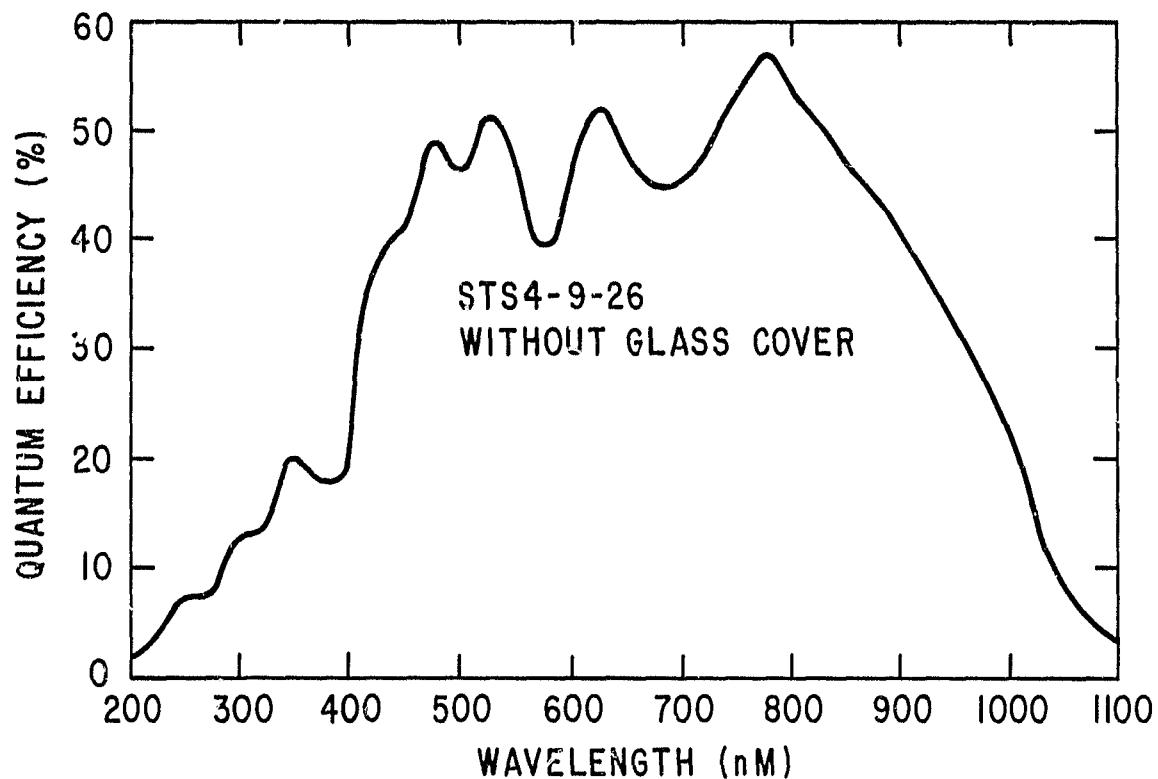


Figure 12. UV Extended Spectral Quantum Efficiency

Table 1

Temporal Noise Source	Equivalent Input Noise (Nanovolts/root Hertz)
Row Select Switch	1.5
On-chip Source Follower	2.3
2N5565 J-Fet Source Follower	1.9
AD818 Amplifier Transistor	2.6
RMS Total	4.2

The total noise can be calculated by integrating the noise power spectral density multiplied by the system transfer function. The noise power is given by:

$$e_n^2 = \int_0^{\infty} \left[ \frac{K}{f} + e_j^2 \right] \left[ 1 - \cos \left( P_i \frac{f}{f_s} \right) \right] \left[ \frac{1}{1 + \left( \frac{f}{f_c} \right)^2} \right] df \quad (1)$$

where:

$\left[ \frac{K}{f} + e_j^2 \right]$  is the noise power spectrum

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$\left[1 - \cos\left(P_f \frac{f}{f_s}\right)\right]$  is the correlated double sampling transfer function  
 $\left[\frac{1}{1 + (\frac{f}{f_c})^2}\right]$  is the amplifier bandwidth limiting

and:

$$K = \text{I/f noise constant} = 1.2 \times 10^{-12} \text{ V}^2$$

$$e_j = \text{total Johnson noise} = 4.2 \times 10^{-9} \text{ V/Hz}^{1/2}$$

$$f_s = \text{sampling frequency} = 5000 \text{ Hz}$$

$$f_c = \text{amplifier cutoff frequency} = 8000 \text{ Hz}$$

A plot of the noise spectral density before and after signal processing is shown in Figure 14. A numerical integration of equation (1) from 10 Hertz to 1 MegaHertz results in a noise voltage of 1.7 microvolts. Since a differential amplifier and frame differencing are used, the noise voltage is doubled. The noise charge at the on-chip sense line is simply the noise voltage times the sense capacitance. In terms of noise electrons referred to the charge packet in the array,

$$n = \frac{C_s \times v_n}{(q \times E_{ro})}$$

where:

$$C_s = \text{Sense capacitance} = 10.8 \times 10^{-12} \text{ F}$$

$$v_n = \text{noise voltage} = 3.4 \times 10^{-6} \text{ V}$$

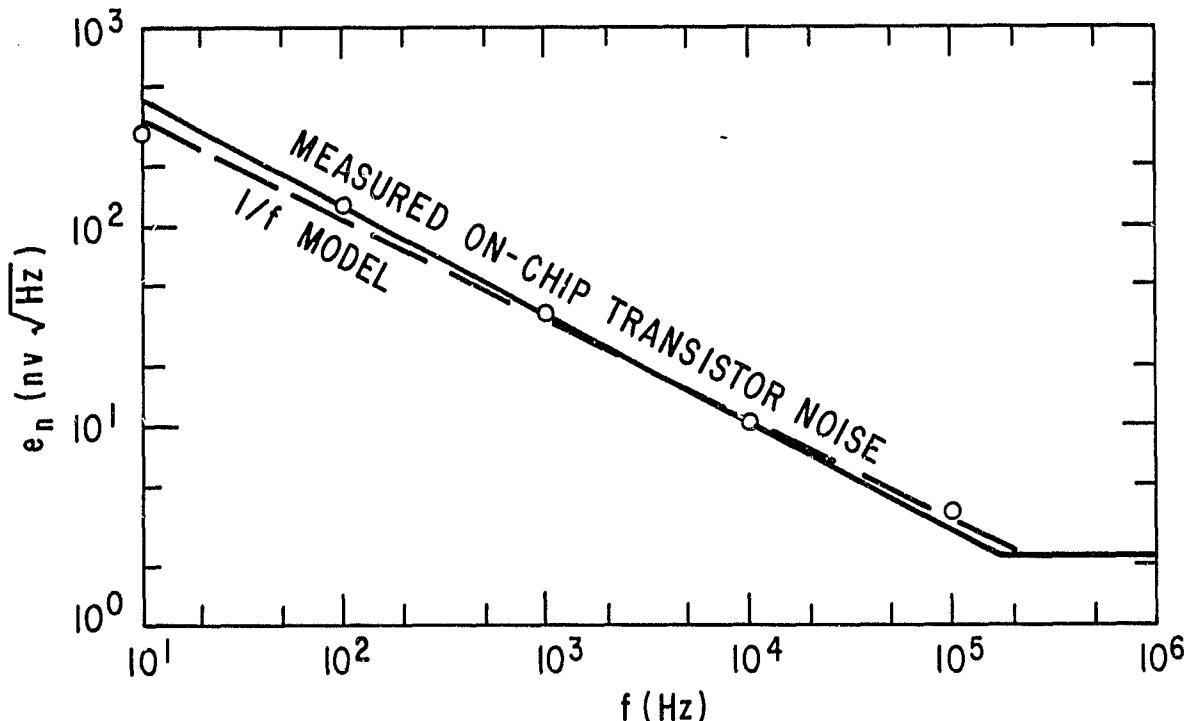


Figure 13. Transistor Noise Spectral Density

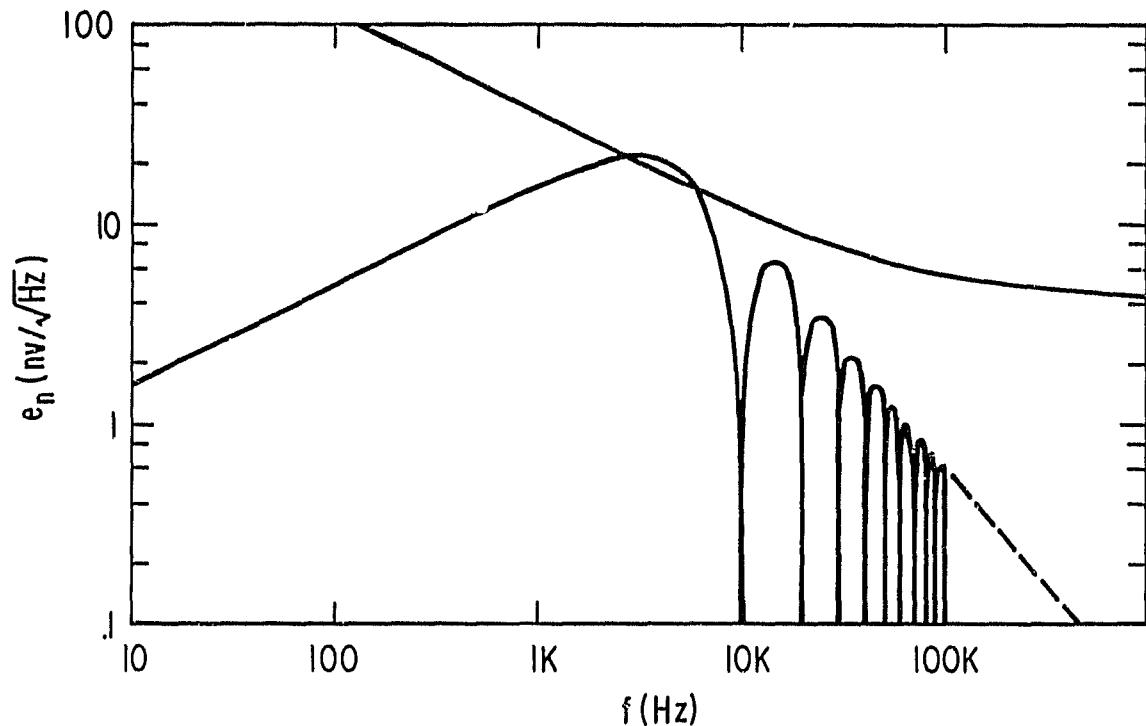


Figure 14. Total Noise Spectral Density Before and After Signal Processing

$$q = \text{electronic charge} = 1.6 \times 10^{-19} C$$

$$E_{ro} = \text{readout efficiency} = .747$$

The calculated number of noise electrons referred to the charge packet in the array is 296 for a single read, and 37 for 64 nondestructive readout operations. The measured values for a 4×4 sub array read out in the track mode are given in Table 2.

#### 6.3.4 Fixed Pattern Noise

Spatial variations in row-column crossover capacitance and in bias charge at sensing sites (pixels) in the CID array result in a background pattern in the absence of signal called fixed pattern noise. Two components of this noise have been observed in the ST256E output signals. The first component is column oriented and is the result of unequal coupling of the four column enable drive lines (E1 through E4) to the sense lines. This component repeats for each 4×4 subarray readout and can be subtracted from the outputs. The second component varies from pixel-to-pixel across the array and is removed from the data when the frame difference is taken. The magnitude of the second component varies from 0.2 volts peak-to-peak (4,000 electrons rms) adjacent to the compensation row to 0.8 volts peak-to-peak (16,000 electrons rms) elsewhere in the array. The main effect of this fixed pattern noise is to reduce the range available for signal at the analog-to-digital converter.

#### 6.3.5 Dark Current

The average room temperature dark current measured on arrays from lot STS4 ranged from .37 to .77 nanoamps per square centimeter except for device STS4-6-24 which had an average dark current of 2.6 nanoamps per square centimeter. Localized regions of high dark current (bright spots) are present to varying degrees with this lot of imagers and is attributed to defects in the starting silicon.

**Table 2**  
**Device STS4-6-13**

**Temporal Noise (T = 23.5 C):**

Mean (Carriers)			
1824.74	1588.13	1812.06	1533.74
1808.81	1490.57	2117.11	1637.58
1802.28	1527.81	1556.85	1565
1966.06	1589.65	1733.86	1503.3

RMS Noise (Carriers)			
63.3628	68.1849	69.068	61.7789
66.0552	73.8415	82.3465	59.3831
63.5482	62.588	63.6022	64.8868
68.2364	69.7306	61.6028	58.4498

Avg. Mean	Avg. Noise
1691.1	66.0416

**Temporal Noise (T = .1 C):**

Mean (Carriers)			
847.492	452.057	261.156	304.572
838.705	267.191	273.421	305.318
879.335	441.549	436.615	386.222
930.011	449.128	451.613	344.652

RMS Noise (Carriers)			
44.3039	52.8901	46.9923	47.6504
54.2826	52.1647	49.5088	51.3946
46.8922	44.3037	45.9558	46.7094
50.7872	47.4062	47.357	53.7509

Avg. Mean	Avg. Noise
491.815	48.8969

**Temporal Noise (T = -10C):**

Mean (Carriers)			
826.547	438.407	411.037	274.273
665.519	372.945	238.276	259.15
984.948	474.671	330.541	208.492
923.71	479.623	304.697	319.376

RMS Noise (Carriers)			
47.7512	53.0035	49.9027	40.6375
52.221	55.0489	62.7751	57.1029
49.7957	43.6554	46.5069	42.6541
41.5405	46.0072	44.6672	46.2975

Avg. Mean	Avg. Noise
469.513	48.7173

## 7. GENERAL PROGRAM ASSESSMENT

The intent of this program was to improve the performance of the CID 256×256 star-tracking sensor. The improvements sought are detailed in section 3.2 and the results achieved are assessed here.

1. Scanner Design - The basic scanner design has been improved and reliable operation has been achieved.
2. Clamp Scanner - A row clamp scanner has been added such that extended objects (general scenes) can be imaged.
3. On-chip Preamplifier Transistors - Preamplifier transistors have been incorporated in the sensor and immunity from external interfering signals has been greatly improved. The ST256E sensor has been operated at the end of 8 inches of cable with no performance degradation. The low frequency noise (1/f noise) of these transistors is somewhat higher than expected. The expected noise level of 30 electrons has not been achieved. The noise level calculated using the achieved 1/f noise spectrum is 37 electrons; the measured noise levels range between 48 and 71 electrons for various arrays.
4. Compensation Line - The compensation line drain has been added as described in section 3.2. This P<sup>+</sup> drain is in the N<sup>-</sup> thin oxide implant region and the resulting P<sup>+</sup>N<sup>+</sup> diode has an avalanche breakdown voltage of 8 volts. This breakdown voltage is very close to the 7.5 volt operating level. A mask change has been made to eliminate the offending junction in future lots processed. The desired capacitive balance of the compensation line with the four signal lines was not achieved with this lot. A change in the aluminum mask was made to improve the capacitive balance in future lots of imagers.
5. Narrow Electrodes - Narrow electrodes have been used successfully in this design. These narrow electrodes, coupled with the thin oxide implant, fine grain polysilicon and anti-reflection coating have resulted in quantum efficiencies in the 50 percent range; usable response from 200 to 1100 nanometers, and reduced fixed-pattern-noise. The 500,000 electron storage capacity design goal for the narrow electrode structure has been achieved.

The most obvious problem with this lot of imagers is the large number of bright spots encountered. This has been a problem with lots previously processed on bulk silicon and is attributed to defects in the wafers as received from the vendor. We know of no way to screen wafers for bright spots short of fabricating imagers on sample wafers. If bulk imagers were processed on a regular basis, this sampling could be done and silicon vendors could be qualified as is the case with our commercial, epitaxial CID imagers. It may also be possible to improve the in-process gettering of silicon defects.

## 8. CONCLUSIONS

The objectives of this program have, in general, been achieved. Problems that were encountered with capacitance balance and avalanche breakdown voltage did not degrade performance significantly, and the sensor photomasks have been changed to correct these problems. The temporal noise level is somewhat higher than desired, but well within the high performance range needed for star-tracking applications. The spectral quantum efficiency achieved is considered outstanding. The design of a hermetic package with integral thermoelectric cooler and the use of on-chip preamplifiers has resulted in a sensor that should be reliable and easy to incorporate in tracking systems.

## 9. REFERENCES

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- [2] Burke, H.K., Michon, G.J., Tomlinson, H.W., Vogelsong, T.L., Grafinger, A., and Wilson, R., "Design, Fabrication, and Delivery of a Charge Injection Device as a Stellar Tracking Device," Contract NAS8-32801, SRD-78-171, April 1979.
- [3] Michon, G.J., Burke, H.K., Vogelsong, T.L., and Wang, K., "Study of Noise in CID Array Systems," Contract N00173-77-C-0054, SRD-78-156, November 1978.
- [4] White, M.H., Lampe, D.R., Blaha, F.C., and Mack, I.A., "Characterization of Surface Channel CCD Image Arrays at Low Light Levels," *IEEE Journal of Solid State Circuits* SC-9, 1-13.

## Microcomputer Assembly Language Program

CROMEMCO C10S Z80 ASSEMBLER version 02.15

PAGE 0001

```

0001 ; 7/21/83 STARS
0002 ;
0003 ; STAR TRACKER CONTROLLER
0004 ; FOR THE ST256 DEVICE
0005 ;
0006 ; B=PIXEL ROW LOCATION
0007 ; C=PIXEL COLUMN LOCATION
0008 ; D,E=DELAY TIME
0009 ; H,L=MEMORY LOCATION
0010 ;
0011 ; I/O PORT DEFINITIONS:
0012 ; 04H =FRONT PANEL LED'S AND SWITCHES
0013 ; 20-22H=CONTROL SIGNALS TO CAMERA BOARD
0014 ; 24-26H=A/D CONTROL AND DATA
0015 ; 28H =A/D START CONVERSION STROBE
0016 ;
0800 C30008 0017 STARS: JP START
0803 0018 ORG 2340H
2340 10 0019 COL: DEFB 16 ;PIXEL COLUMN LOCATION
2341 10 0020 ROW: DEFB 16 ;PIXEL ROW LOCATION
2342 40 0021 NSUM: DEFB 64 ;NUMBER OF SUMS PER PIXEL
(2300) 0022 BASE: EQU 2300H ;TEMPORARY STORAGE MEMORY
(0004) 0023 LED: EQU 04H ;SWITCH/LED PORT
(0028) 0024 STROBE: EQU 28H ;A/D START CONVERSION STROBE
2343 0025 ORG 800H
0026 ;
0027 ;*****
0028 ; THIS SECTION CONTAINS THE
0029 ; MACRO DEFINITIONS
0030 ;*****
0031 ;
0032 GETDATA:MACRO ;SUM AND STORE DATA MACRO
0033 IN A,20H ;GET LOWER 8 BITS OF DATA
0034 ADD (HL)
0035 LD (HL),A ;SUM AND STORE LOW 8 BITS
0036 INC L
0037 IN A,21H ;GET UPPER 4 BITS OF DATA
0038 OUT STROBE,A;START NEXT CONVERSION
0039 ADC (HL)
0040 LD (HL),A ;SUM AND STORE MID 8 BITS
0041 INC L
0042 LD A,0
0043 ADC (HL)
0044 LD (HL),A ;SUM AND STORE TOP 8 BITS
0045 INC L
0046 MEND
0047 ;
0048 ;*****
0049 ; THIS SECTION PERFORMS THE INJECT SEQUENCE
0050 ; TIMING, AND CALLS THE "BLOCK" SUBROUTINE
0051 ; TO READ THE BACKGROUND AND SIGNAL
0052 ;*****
0053 ;
0800 C31908 0054 START: JP INIT
0803 C32308 0055 JP INIT2
0806 C32F08 0056 JP CID
0809 C3E609 0057 JP MOVE

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080C C3EF09	0058	JP	CLEAR
080F C3FC09	0059	JP	PICT
0812 C33E0A	0060	JP	COPY
0815 C3470A	0061	JP	SUBBKG
0818 C9	0062	RET	
0819 0610	0063 INIT:	LD	B,16 ;INITIALIZE ROW
081B 0E2B	0064	LD	C,43 ;INITIALIZE COLUMN
081D 114000	0065	LD	DE,64 ;INITIALIZE NO. OF SUMS
0820 C32F08	0066	JP	CID
0823 3A4123	0067 INIT2:	LD	A,(ROW) ;INITIALIZE ROW
0826 47	0068	LD	B,A
0827 3A4023	0069	LD	A,(COL) ;INITIALIZE COLUMN
082A 4F	0070	LD	C,A
082B 3A4223	0071	LD	A,(NSUM);INITIALIZE NO. OF SUMS
082E 5F	0072	LD	E,A
082F 7B	0073 CID:	LD	A,E
0830 324223	0074	LD	(NSUM),A
0833 3E01	0075	LD	A,1
0835 D304	0076	OUT	LED,A ;LIGHT GREEN LED
0837 3E47	0077 CO:	LD	A,47H ;REST,RVG,CVG,IG ON
0839 D325	0078	OUT	25H,A
083B 3E67	0079	LD	A,67H ;CVD ON
083D D325	0080	OUT	25H,A
083F 3E77	0081	LD	A,77H ;RVD ON
0841 D325	0082	OUT	25H,A
0843 113200	0083	LD	DE,50
0846 CDDF09	0084	CALL	DELAY
0849 3E67	0085	LD	A,67H ;RVD OFF
084B D325	0086	OUT	25H,A
084D 3E47	0087	LD	A,47H ;CVD OFF
084F D325	0088	OUT	25H,A
0851 110500	0089	LD	DE,5
0854 CDDF09	0090	CALL	DELAY
0857 212F23	0091	LD	HL, BASE+47
085A 3EFF	0092	LD	A,OFFH
085C 77	0093 C1:	LD	(HL),A ,CLEAR TEMPORARY MEMORY
085D 2D	0094	DEC	L
085E F23C08	0095	JP	P,C1
0861 CD8408	0096	CALL	BLOCK ;READ BACKGROUND
0864 212F23	0097	LD	HL, BASE+47
0867 7E	0098 C2:	LD	A,(HL) ;NEGATE BKG IN TEMP MEMORY
0868 2F	0099	CPL	
0869 77	0100	LD	(HL),A
086A 2D	0101	DEC	L
086B F26708	0102	JP	P,C2
086E CD8408	0103 C3:	CALL	BLOCK ;READ SIGNAL
0871 3E02	0104	LD	A,2 ;LIGHT RED LED
0873 D304	0105	OUT	LED,A
0875 DB04	0106	IN	A,LED ;CHECK SWITCHES
0877 E603	0107	AND	3
0879 C23708	0108	JP	NZ,CO ;REPEAT SEQUENCE?
087C 3E67	0109	LD	A,67H ;CVD ON, RVD OFF (IDLE)
087E D325	0110	OUT	25H,A
0880 AF	0111	XOR	A,A ;TURN OFF LED'S
0881 D304	0112	OUT	LED,A
0883 C9	0113	RET	
	0114 ;		

```

0115 ;*****THIS SECTION RUNS THE PHASE LINES TO CHOOSE
0116 ; THE PIXEL SPECIFIED BY THE B,C REGISTERS,
0117 ; CALLS THE "READ" SUBROUTINE TO READ EACH
0118 ; COLUMN 64 TIMES, AND RUNS THE PHASE LINES
0119 ; TO CLEAR BOTH SCANNERS
0120 ;*****0121 ;*****0122 ;
0884 CD7509 0123 BLOCK: CALL PHASIN ;RUN REGISTERS TO CHOOSE BLOCK
0887 3E44 0124 LD A,44H ;REST,IG ON; CVG,RVG OFF
0889 D325 0125 OUT 25H,A
088B C5 0126 PUSH BC
088C 210023 0127 LD HL, BASE
088F 011000 0128 LD BC,10H ;READ COLUMN 1
0892 CDBA08 0129 CALL READ
0895 012000 0130 LD BC,20H ;READ COLUMN 2
0898 CDBA08 0131 CALL READ
089B 014000 0132 LD BC,40H ;READ COLUMN 3
089E CDBA08 0133 CALL READ
08A1 018000 0134 LD BC,80H ;READ COLUMN 4
08A4 CDBA08 0135 CALL READ
08A7 C1 0136 POP BC
08A8 3E47 0137 LD A,47H ;REST,IG,RVG,CVG ON
08AA D325 0138 OUT 25H,A
08AC 1642 0139 LD D,66
08AE 3E0A 0140 LD A,0AH
08B0 210A05 0141 LD HL,050AH
08B3 CDC909 0142 CALL PHASE ;RUN OUT BOTH REGISTERS
08B6 AF 0143 XOR A ;TURN OFF BOTH PHASES
08B7 D326 0144 OUT 26H,A
08B9 C9 0145 RET
0146 ;
0147 ;*****THIS SECTION READS THE 4 ROWS BY
0148 ; 1 COLUMN, SUMS EACH PIXEL 64 TIMES,
0149 ; AND STORES THE 4 18-BIT SUMS IN RAM
0150 ; LOCATIONS 2300-232FH
0151 ;*****0152 ;*****0153 ;
08BA 1602 0154 READ: LD D,2 ;USE D AS A COUNTDOWN
08BC 78 0155 R1: LD A,B ;TURN E LINES OFF
08BD D324 0156 OUT 24H,A
08BF 3E05 0157 LD A,5
08C1 3D 0158 D1: DEC A ;DELAY
08C2 C2C108 0159 JP NZ,D1
08C5 3E04 0160 LD A,04H ;IG ON; RESTORE OFF
08C7 D325 0161 OUT 25H,A
08C9 3E00 0162 LD A,00H ;IG OFF
08CB D325 0163 OUT 25H,A
08CD 3E40 0164 LD A,40H ;RESTORE ON
08CF D325 0165 OUT 25H,A
08D1 3E21 0166 LD A,0FH
08D3 3D 0167 D2: DEC A ;DELAY
08D4 C2D308 0168 JP NZ,D2
08D7 AF 0169 XOR A ;REST OFF
08D8 D325 0170 OUT 25H,A
08DA 79 0171 LD A,C ;DRIVE E LINE

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08DB	D324	0172	OUT	24H,A	;AND GET CHANNEL 0
08DD	3E11	0173	LD	A,0DH	
08DF	3D	0174 D3:	DEC	A	;DELAY
08E0	C2DF08	0175	JP	NZ,D3	
08E3	15	0176	DEC	D	
08E4	C2BC08	0177	JP	NZ,R1	;DONE STARTUP YET?
08E7	3A4223	0178	LD	A,(NSUM);LOAD NUMBER OF SUMS	
08EA	57	0179	LD	D,A	
08EB	E5	0180 R2:	PUSH	HL	
08EC	3E80	0181	LD	A,80H	;SAMPLE
08EE	D325	0182	OUT	25H,A	
08F	3E00	0183	LD	A,0	;DELAY
08F	3E00	0184	LD	A,0	
08F	3E00	0185	LD	A,0	
08F6	D325	0186	OUT	25H,A	;HOLD
08F8	D328	0187	OUT	STROBE,A;START A/D CONVERSION	
08FA	D324	0188	OUT	24H,A	;TURN E LINE OFF
08FC	3E04	0189	LD	A,04H	;IG ON; RESTORE OF-
08FE	D325	0190	OUT	25H,A	
0900	3E00	0191	LD	A,00H	;IG OFF
0902	D325	0192	OUT	25H,A	
0904	3E40	0193	LD	A,40H	;RESTORE ON
0906	D325	0194	OUT	25H,A	
0908	78	0195	LD	A,B	
0909	F601	0196	OR	1	;GET CHANNEL 1
090B	D324	0197	OUT	24H,A	
090D	0198	GETDATA			;SUM AND STORE DATA
090D	DB20	0199+	IN	A,20H	;GET LOWER 8 BITS OF DATA
090F	86	0200+	ADD	(HL)	
0910	77	0201+	LD	(HL),A	;SUM AND STORE LOW 8 BITS
0911	2C	0202+	INC	L	
0912	DB21	0203+	IN	A,21H	;GET UPPER 4 BITS OF DATA
0914	D328	0204+	OUT	STROBE,A;START NEXT CONVERSION	
0916	8E	0205+	ADC	(HL)	
0917	77	0206+	LD	(HL),A	;SUM AND STORE MID 8 BITS
0918	2C	0207+	INC	L	
0919	3E00	0208+	LD	A,0	
091B	8E	0209+	ADC	(HL)	
091C	77	0210+	LD	(HL),A	;SUM AND STORE TOP 8 BITS
091D	2C	0211+	INC	L	
091E	78	0212	LD	A,B	
091F	F602	0213	OR	2	;GET CHANNEL 2
0921	D324	0214	OUT	24H,A	
0923	0215	GETDATA			;SUM AND STORE DATA
0923	DB20	0216+	IN	A,20H	;GET LOWER 8 BITS OF DATA
0925	86	0217+	ADD	(HL)	
0926	77	0218+	LD	(HL),A	;SUM AND STORE LOW 8 BITS
0927	2C	0219+	INC	L	
0928	DB21	0220+	IN	A,21H	;GET UPPER 4 BITS OF DATA
092A	D328	0221+	OUT	STROBE,A;START NEXT CONVERSION	
092C	8E	0222+	ADC	(HL)	
092D	77	0223+	LD	(HL),A	;SUM AND STORE MID 8 BITS
092E	2C	0224+	INC	L	
092F	3E00	0225+	LD	A,0	
0931	8E	0226+	ADC	(HL)	
0932	77	0227+	LD	(HL),A	;SUM AND STORE TOP 8 BITS
0933	2C	0228+	INC	L	

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0934	AF	0229	XOR	A,A	
0935	D325	0230	OUT	25H,A	;RESTORE OFF
0937	79	0231	LD	A,C	;DRIVE E LINES
0938	F603	0232	OR	3	;GET CHANNEL 3
093A	D324	0233	OUT	24H,A	
093C		0234	GETDATA		;SUM AND STORE DATA
093C	DB20	0235+	IN	A,20H	;GET LOWER 8 BITS OF DATA
093E	86	0236+	ADD	(HL)	
093F	77	0237+	LD	(HL),A	;SUM AND STORE LOW 8 BITS
0940	2C	0238+	INC	L	
0941	DB21	0239+	IN	A,21H	;GET UPPER 4 BITS OF DATA
0943	D328	0240+	OUT	STROBE,A;START NEXT CONVERSION	
0945	8E	0241+	ADC	(HL)	
0946	77	0242+	LD	(HL),A	;SUM AND STORE MID 8 BITS
0947	2C	0243+	INC	L	
0948	3E00	0244+	LD	A,0	
094A	8E	0245+	ADC	(HL)	
094B	77	0246+	LD	(HL),A	;SUM AND STORE TOP 8 BITS
094C	2C	0247+	INC	L	
094D	79	0248	LD	A,C	
094E	F600	0249	OR	0	;GET CHANNEL 0
0950	D324	0250	OUT	24H,A	
0952		0251	GETDATA		;SUM AND STORE DATA
0952	DB20	0252+	IN	A,20H	;GET LOWER 8 BITS OF DATA
0954	86	0253+	ADD	(HL)	
0955	77	0254+	LD	(HL),A	;SUM AND STORE LOW 8 BITS
0956	2C	0255+	INC	L	
0957	DB21	0256+	IN	A,21H	;GET UPPER 4 BITS OF DATA
0959	D328	0257+	OUT	STROBE,A;START NEXT CONVERSION	
095B	8E	0258+	ADC	(HL)	
095C	77	0259+	LD	(HL),A	;SUM AND STORE MID 8 BITS
095D	2C	0260+	INC	L	
095E	3E00	0261+	LD	A,0	
0960	8E	0262+	ADC	(HL)	
0961	77	0263+	LD	(HL),A	;SUM AND STORE TOP 8 BITS
0962	2C	0264+	INC	L	
0963	E1	0265	POP	HL	
0964	15	0266	DEC	D	
0965	C2EB08	0267	JP	NZ,R2	;DONE ALL SUMS YET?
0968	3E00	0268	LD	A,0	;TURN OFF E LINES
096A	D324	0269	OUT	24H,A	
096C	3E47	0270	LD	A,47H	;RESTORE, RVG, CVG, IG ON
096E	D325	0271	OUT	25H,A	
0970	010C00	0272	LD	BC,12	
0973	09	0273	ADD	HL,BC	
0974	09	0274	RET		
		0275	;		
		0276	*****		
		0277	; THIS SECTION RUNS THE PHASE LINES		
		0278	; TO ADDRESS THE CHOSEN PIXEL		
		0279	*****		
		0280	;		
0975	C5	0281	PHASIN: PUSH	BC	;SAVE PIXEL ADDRESS
0976	1E00	0282	LD	E,0	
0978	04	0283	INC	B	;WORK ON ROW ADDRESS
0979	CB38	0284	SRL	B	
097B	04	0285	INC	B	

097C	CB38	0286	SRL	B		
097E	D28609	0287	JP	NC,F1	;CHECK UP/DOWN	
0981	CBF3	0288	SET	6,E	;SET TO UP	
0983	C38B09	0289	JP	F2		
0986	CBB3	0290	F1:	RES	6,E	;SET TO DOWN
0988	C38B09	0291	JP	F2		
098B	OC	0292	F2:	INC	C	;WORK ON COLUMN ADDRESS
098C	CB39	0293	SRL	C		
098E	OC	0294	INC	C		
098F	CB39	0295	SRL	C		
0991	D29909	0296	JP	NC,F3	;CHECK LEFT/RIGHT	
0994	CBFB	0297	SET	7,E	;SET TO LEFT	
0996	C39E09	0298	JP	F4		
0999	CBBB	0299	F3:	RES	7,E	;SET TO RIGHT
099B	C39E09	0300	JP	F4		
099E	3E82	0301	F4:	LD	A,130	
09A0	90	0302	SUB	B		
09A1	91	0303	SUB	C		
09A2	57	0304	LD	D,A		
09A3	0F	0305	XOR	A		
09A4	210000	0306	LD	HL,0	;RUN NEITHER PHASE LINE	
09A7	CDC909	0307	CALL	PHASE	; (TO BALANCE TIMING)	
09AA	3E35	0308	LD	A,35H	;VIN,HIN,P1V,P1H ON	
09AC	D326	0309	OUT	26H,A		
09AE	3E30	0310	LD	A,30H	;VIN,HIN ON; P1V,P1H OFF	
09B0	D326	0311	OUT	26H,A		
09B2	50	0312	LD	D,B		
09B3	3E01	0313	LD	A,01H		
09B5	210102	0314	LD	HL,0201H	;RUN VERTICAL REGISTER	
09B8	CDC909	0315	CALL	PHASE	;TO CHOOSE ROW BLOCK	
09B9	51	0316	LD	D,C		
09BC	F604	0317	OR	04H		
09BE	210408	0318	LD	HL,0804H	;RUN HORIZONTAL REGISTER	
09C1	CDC909	0319	CALL	PHASE	;TO CHOOSE COLUMN BLOCK	
09C4	C1	0320	POP	BC	;BRING BACK BLOCK ADDRESS	
09C5	B3	0321	OR	E	;CHOOSE U/D AND L/R	
09C6	D326	0322	OUT	26H,A		
09C8	C9	0323	RET			
		0324	;			
		0325	*****			
		0326	;	THIS SECTION PERFORMS THE		
		0327	;	TIMING OF THE PHASE LINES		
		0328	;	*****		
		0329	;			
09C9	AD	0330	PHASE:	XOR	L	;PHASE LINE SUBROUTINE
09CA	D326	0331	OUT	26H,A	;PHASE 2 ON	
09CC	AC	0332	XOR	H		
09CD	D326	0333	OUT	26H,A	;PHASE 2 OFF	
09CF	15	0334	DEC	D	;DONE YET?	
09D0	C2D409	0335	JP	NZ,PH1		
09D3	C9	0336	RET			
09D4	AC	0337	PH1:	XOR	H	
09D5	D326	0338	OUT	26H,A	;PHASE 1 ON	
09D7	AD	0339	XOR	L		
09D8	D326	0340	OUT	26H,A	;PHASE 1 OFF	
09DA	15	0341	DEC	D	;DONE YET?	
09DB	C2C909	0342	JP	NZ,PHASE		

09DE C9 0343 RET ORIGINAL PAGE IS  
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0344 ;

0345 ;\*\*\*\*\*THIS SUBROUTINE PERFORMS A DELAY

0346 ; OF ABOUT 4 MICROSECONDS PER LOOP

0347 ;\*\*\*\*\*

0348 ;\*\*\*\*\*

0349 ;

09DF 1B 0350 DELAY: DEC DE

09E0 7B 0351 LD A,E

09E1 B2 0352 OR D

09E2 C2DF09 0353 JP NZ,DELAY

09E5 C9 0354 RET

0355 ;

0356 ;\*\*\*\*\*

0357 ; THIS ROUTINE MOVES THE DATA FROM

0358 ; TEMPORARY STORAGE TO A PERMANENT

0359 ; STORAGE LOCATION SPECIFIED BY THE

0360 ; DE REGISTERS

0361 ;\*\*\*\*\*

0362 ;

09E6 210023 0363 MOVE: LD HL,2300H

09E9 013000 0364 LD BC,48

09EC EDB0 0365 LDIR

09EE C9 0366 RET

0367 ;

0368 ;\*\*\*\*\*

0369 ; THIS ROUTINE CLEARS THE CONTENTS

0370 ; OF MEMORY STARTING AT DE AND

0371 ; PROCEEDING TO BC+DE

0372 ;\*\*\*\*\*

0373 ;

09EF 62 0374 CLEAR: LD H,D

09F0 6E 0375 LD L,E

09F1 1600 0376 LD D,0

09F3 72 0377 CL1: LD (HL),D

09F4 23 0378 INC HL

09F5 0B 0379 DEC BC

09F6 79 0380 LD A,C

09F7 B0 0381 OR B

09F8 C2F309 0382 JP NZ,CL1

09FB C9 0383 RET

0384 ;

0385 ;\*\*\*\*\*

0386 ; THIS ROUTINE TAKES THE DATA FROM TEMPORARY

0387 ; STORAGE, PICKS OUT THE 8 BITS/PIXEL TO BE

0388 ; DISPLAYED (SPECIFIED BY BC), AND STORES

0389 ; THEM IN MEMORY (SPECIFIED BY HL) FOR

0390 ; PICTURE DISPLAY

0391 ;\*\*\*\*\*

0392 ;

09FC 210023 0393 PICT: LD HL,2300H

09FF 78 0394 LD A,B ;LOAD LSB CHOICE

0A00 FE09 0395 CP 9 ;GREATER THAN EIGHT BIT SHIFT?

0A02 DA080A 0396 JP C,P1

0A05 23 0397 INC HL ;IF SO SHIFT ONE BYTE

0A06 D608 0398 SUB B

0A08 2F 0399 P1: CPL

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0A09 D6F7      0400      SUB      247      ;8 MINUS LSB CHOICE
0A0B 47        0401      LD       B,A      ;SAVE NUMBER OF SHIFTS
0A0C E5        0402 P2:    PUSH     HL
0A0D D5        0403 P3:    PUSH     DE      ;SAVE PICTURE STORAGE ADDRESS
0A0E 5E        0404      LD       E,(HL)   ;PULL DATA OUT OF TEMP STORAGE
0A0F 23        0405      INC      HL      ;AND STORE IT IN DE REGISTERS
0A10 56        0406      LD       D,(HL)
0A11 78        0407      LD       A,B      ;BRING BACK NO. OF SHIFTS
0A12 B7        0408      OR       A
0A13 CA1DOA    0409      JP       Z,P5    ;IF NO SHIFTS, JUMP AHEAD
0A16 EB        0410      EX       DE,HL
0A17 29        0411 P4:    ADD     HL,HL    ;SHIFT RIGHT
0A18 3D        0412      DEC     A
0A19 C2170A    0413      JP       NZ,P4
0A1C EB        0414      EX       DE,HL
0A1D 79        0415 P5:    LD       A,C      ;ADD ZERO LEVEL BIAS TO PICTURE
0A1E 82        0416      ADD     D
0A1F D1        0417      POP     DE      ;BRING BACK PICT STORAGE ADDR
0A20 12        0418      LD       (DE),A   ;STORE PIXEL
0A21 13        0419      INC     DE      ;NEXT COLUMN DATA
0A22 7D        0420      LD       A,L
0A23 C60B      0421      ADD     11
0A25 6F        0422      LD       L,A
0A26 FE2F      0423      CP      47      ;DONE ALL 4 COLUMNS YET?
0A28 DA0DOA    0424      JP       C,P3
0A2B E1        0425      POP     HL      ;NEXT ROW DATA
0A2C 23        0426      INC     HL
0A2D 23        0427      INC     HL
0A2E 23        0428      INC     HL
0A2F 7D        0429      LD       A,L
0A30 FE0C      0430      CP      12      ;DONE ALL FOUR ROWS YET?
0A32 D0        0431      RET     NC
0A33 3E7C      0432      LD       A,124   ;SET MEM ADDR FOR NEXT BLOCK
0A35 83        0433      ADD     E
0A36 5F        0434      LD       E,A
0A37 3E00      0435      LD       A,0
0A39 8A        0436      ADC     D
0A3A 57        0437      LD       D,A
0A3B C30COA    0438      JP       P2
0439 ;
0440 ;*****
0441 ; THIS ROUTINE COPIES THE PICTURE
0442 ; FROM ONE LOCATION IN MEMORY
0443 ; INTO ANOTHER LOCATION
0444 ;*****
0445 ;
0A3E 62        0446 COPY:   LD       H,D
0A3F 6B        0447      LD       L,E
0A40 7A        0448      LD       A,D
0A41 C640      0449      ADD     40H
0A43 57        0450      LD       D,A
0A44 EDB0      0451      LDIR
0A46 C9        0452      RET
0453 ;
0454 ;*****
0455 ; THIS ROUTINE SUBTRACTS THE BACKGROUND
0456 ; PICTURE FROM THE MAIN PICTURE

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0457 ; REGISTERS DE CONTAIN THE START ADDRESS  
0458 ; OF THE MAIN PICTURE, BC IS THE NUMBER OF  
0459 ; PIXELS, THE BKG PICTURE IS OFFSET  
0460 ; FROM THE MAIN PICTURE BY 4000H  
0461 ;\*\*\*\*\*  
0462 ;

0A47	62	0463	SUBBKG: LD	H,D
0A48	6B	0464	LD	L,E
0A49	7C	0465	LD	A,H
0A4A	C640	0466	ADD	40H
0A4C	67	0467	LD	H,A
0A4D	1A	0468	S1: LD	A,(DE)
0A4E	96	0469	SUB	(HL)
0A4F	C620	0470	ADD	20H
0A51	12	0471	LD	(DE),A
0A52	23	0472	INC	HL
0A53	13	0473	INC	DE
0A54	0B	0474	DEC	BC
0A55	79	0475	LD	A,C
0A56	B0	0476	OR	B
0A57	C24D0A	0477	JP	NZ,S1
0A5A	C9	0478	RET	

Errors 0

end of assembly

A.

# Basic Sensor Evaluation Program

1000 INPUT "STAR #: 0-9999"  
1100 DEFINE A=0:DEF DBL S=T  
1200 A=&H800  
130 B=8  
140 NS=4  
150 A1=A+6:A2=A+9:A3=A+12:A4=A+15  
155 DIM RM(3,3),RS(3,3)  
160 PRINT  
170 PRINT "CID STAR TRACKER"  
180 INPUT "STORE PICTURE (1), TEMPORAL NOISE (2), TOTAL NOISE (3)":WP  
200 ON WP GOTO 1000,2000,3000,5000,6000  
210 GOTO 190  
1000 INPUT "FIRST PIXEL: ROW,COLUMN (0-255,0-255)":FR,FC  
1010 INPUT "LAST PIXEL":LR,LC  
1020 IF (LC-FC)<128 THEN 1050  
1030 PRINT "TOO MANY COLUMNS (>128)"  
1040 GOTO 1000  
1050 IF (LR-FR)<92 THEN 1090  
1060 PRINT "TOO MANY ROWS (>92)"  
1070 GOTO 1000  
1090 INPUT "SPECIFY LSB LOCATION (0-10)":P1  
1100 BP=B+256\*P1  
1130 CALL A3,&H9000,&H2F7F  
1140 FOR I=0TO0  
1150 CALL A1,NS,256\*FR+FC  
1160 NEXT  
1170 FOR I=FR TO LR STEP 4  
1180 M=&H9000+128\*(I-FR)  
1190 FOR J=FC TO LC STEP 4  
1200 CALL A1,NS,256\*I+J  
1210 CALL A4,M,BP  
1220 M=M+4  
1230 NEXT:NEXT  
1232 INPUT "HISTOGRAM (Y OR N)":R\$  
1234 IF R\$><"Y"> THEN 1248  
1236 INPUT "NORMALIZATION FACTOR (1-255)":NF  
1238 CALL &HF00,NF  
1240 INPUT "RENORMALIZE (Y OR N)":R\$  
1242 IF R\$="Y" THEN 1236  
1248 INPUT "RETAKE PICTURE (Y OR N)":R\$  
1250 IF R\$="Y" THEN 1130  
1260 GOTO 170  
2000 INPUT "WHICH PIXEL: ROW,COLUMN (0-255,0-255)":FR,FC  
2010 INPUT "OPERATING TEMPERATURE":T  
2020 N=100  
2030 FOR I=0TO0  
2040 CALL A1,NS,256\*FR+FC  
2050 NEXT  
2060 FOR I=0TON-1  
2070 CALL A1,NS,256\*FR+FC  
2080 CALL A2,&H9200+48\*I  
2090 NEXT  
2100 INPUT "RETAKE DATA (Y OR N)":R\$  
2110 IF R\$="Y" THEN 2030  
2120 GOSUB 4000  
2130 INPUT "REPEAT (Y OR N)":R\$  
2140 IF R\$="Y" THEN 2010  
2150 GOTO 170

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3000 INPUT "FIRST PIXEL: ROW,COLUMN (0-255,0-255)":FR,FC
3010 INPUT "LAST PIXEL":LR,LC
3020 N=(LC-FC+4)*(LR-FR+4)
3030 IF N<4081 THEN 3060
3040 PRINT "TOO MUCH DATA (>3600 PIXELS )"
3050 GOTO3000
3060 INPUT "OPERATING TEMPERATURE":T
3070 FOR I=0TO3
3080 CALL A1,NS,256*FR+FC
3090 NEXT
3100 M=&H9200
3110 FOR I=FR TO LR STEP 4
3120 FOR J=FC TO LC STEP 4
3130 CALL A1,NS,256*I+J
3140 CALL A2,M
3150 M=M+48
3160 NEXT:NEXT
3170 INPUT "RETAKE DATA (Y OR N)":R$
3180 IF R$="Y" THEN 3070
3190 GOSUB 4000
3200 INPUT "REPEAT (Y OR N)":R$
3210 IF R$="Y" THEN 3060
3220 GOTO170
4000 PRINT
4010 ON WP GOTO 4020,4020,4040
4020 PRINT "TEMPORAL NOISE (T=""#T;"C)""
4030 GOTO 4050
4040 PRINT "TOTAL NOISE (T=""#T;"C)""
4050 PRINT
4060 M=&H9200
4070 N=100
4080 NN=N-1
4090 NM=NN*48
4100 SC=113.6/NS
4110 PRINT "MEAN (CARRIERS)"
4120 FOR L=0 TO 3
4130 FOR J=0 TO 3
4140 SM=0:SS=0
4150 M1=M+12*J+3*L
4160 M2=M1+NM
4170 FORMM=M1TOM2STEP48
4180 PX=DPEEK(MM)
4190 SM=SM+PX
4200 SS=SS+PX*PX
4210 NEXT
4220 RM(J,L)=SC*SM/N
4230 PRINT RM(J,L)
4240 SD=(SS-SM*SM/N)/NN
4250 RD(J,L)=SC*SQR(ABS(SD))
4260 NEXT:PRINT
4270 NEXT:PRINT
4280 PRINT "RMS NOISE (CARRIERS)"
4290 QM=0:QD=0
4300 FOR L=0 TO 3
4310 FOR J=0 TO 3
4320 QM=QM+RM(J,L)
4330 QD=QD+RD(J,L)
4340 PRINT RD(J,L)
4350 NEXT:PRINT
4360 NEXT:PRINT

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```
4370 PRINT "AVG MEAN","AVG NOISE"
4380 PRINT QM/16, QD/16
4390 PRINT
4400 RETURN
5000 A5=A+18
5010 B1=&H9200
5020 B2=&H2BFF
5030 CALL A5,B1,B2
5040 GOTO 190
6000 A6=A+21
6010 B1=&H9200
6020 B2=&H2BFF
6030 CALL A6,B1,B2
6040 GOTO 190
6050 END
OK
```

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